FORM PTO-1449	SERIAL NO.	CASE NO.
	Not Yet Assigned	9905/30
	10/540, 303	(BIF023241/US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	Herewith	Not Yet Assigned
STATEMENT		2/27
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	A2	6,096,433	08/01/2000	Kikuchi et al.		
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Va	A7	FR 2 819 099 A1	12/28/2000	France		DO
7	A8	EP 0 889 509 A2	01/07/1999	EPO	/	

EXAMINER	OTHER ART – NON PATENT LITERATURE DOCUMENTS						
INITIAL	(Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.						
Lu	K.Y. Ahn et al.,"Growth, Shrinkage, And Stability Of Interfacial Oxide Layers Between Directly Bonded Silicon Wafers," published In Applied Physics A, 50, 1990, pp. 85-94).						
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.